

Gas Plasma Cleaners | RIE-DP Mode, Parallel Plate Electrode

PDC200/210/510

Made in Japan

High frequency output 300W (PDC200)/500W (PDC210/510)

Electrode dimensions 250×170mm (PDC200/210)/410×210mm (PDC510)

Compact plasma cleaners for research and development.

High-performance benchtop plasma cleaners designed for ease of use, suitable for electronic materials and a wide range of R&D applications.

Applications

- Plasma cleaning of CSP, BGA, and COB substrates
- Removal of organic films and metal oxides
- Dry cleaning of printed circuit boards
- Surface/interface activation
- LED packaging

Features

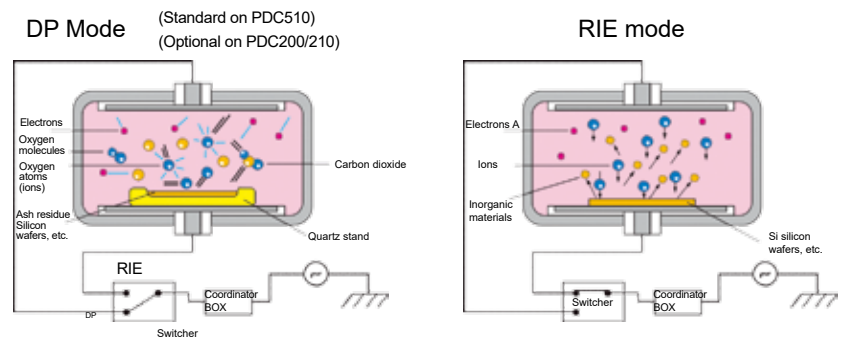
- DP mode (standard on PDC510, optional on PDC200/210)
- RIE mode
- High-uniformity electrode structure
- Simple touch screen controller operation



Internal chamber



Configuration diagram



Specifications

Model	PDC200	PDC210	PDC510
Plasma mode	RIE (DP mode optional)		RIE/DP
Electrode structure	Parallel plate (fixed)		
High frequency output	Max. 300W	Max. 500W	
Frequency	13.56MHz		
Control/display	LCD touch screen		
Reaction chamber dimensions	W400×D250×H150mm		W500×D300×H200mm
Electrode dimensions	W250×D170mm		W410×D210mm
Reaction chamber material	Aluminum		
Reaction gas	2 Systems (Ar, O ₂)		
Filling gas	N ₂ or dry air		
Reaction gas flow control	Flow meter	Mass flow controller	
Vacuum pump	Optional	Oil pump (Approx. 345L/min) standard equipment	Oil pump (Approx. 500L/min) standard equipment
Gas inlet	2 reaction gas, 1 filling gas		
External dimensions	W540×D600×H600mm	W540×D600×H600mm	W700×D700×H1285mm
Weight	Approx. 100kg	Approx. 105kg	Approx. 180kg
Power supply *	Single phase AC100V 10A	3-phase AC200V 6A	3-phase AC200V 8A

* Voltage modifications other than the listed specifications are also available. Please contact us for details.

1 Sterilizers

2 Granulation and Spray Dryers

3 Furnaces

4 Ovens

5 Incubators

6 Plasma Equipment

7 Water Purifiers

8 Baths

9 Water Circulators

10 Rotary Evaporators

11 Stirrers & Shakers

12 Options